



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Seiichi MIYAZAKI

Group Art Unit: 2823

Application No.: 09/913,334

Examiner: G. Fourson III

Filed: August 13, 2001

Docket No.: 110386

For: ETCHANT, ETCHING METHOD AND SEMICONDUCTOR SILICON WAFER

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the August 22, 2003 Office Action, please consider the following:

Amendments to the Claims as reflected in the listing of claims;

Remarks.

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